

Amendments to the Claims

Please cancel claims 1-31.

5 32. (Original) A method of using a micro-mirror device having a reflective element, a pair of electrodes spaced from the reflective element, and a dielectric liquid disposed at least between the reflective element and the pair of electrodes, said method comprising the steps of:
electrically coupling to the pair of electrodes an operational amplifier having an
10 output for coupling to at least one of the pair of electrodes and having inverting and non-inverting inputs;
electrically coupling the reflective element to the inverting input of the operational amplifier to provide feedback; and
applying an analog positioning signal to the non-inverting input of the operational
15 amplifier, whereby the reflective element is positioned at a selected position within a continuous range between a first position and a second position in response to the applied analog positioning signal.

33. (Original) The method of claim 32, further comprising the step of:
20 mixing a dithering signal with said analog positioning signal.

34. (Original) A method of fabricating a micro-mirror device, the method comprising the steps of:
providing a substrate having a surface;
25 providing a plate oriented substantially parallel to the surface of the substrate and spacing the plate from the surface of the substrate, including defining a cavity between the plate and the surface of the substrate;
disposing a dielectric liquid in the cavity; and
interposing a reflective element between the surface of the substrate and the
30 plate, wherein the reflective element is adapted to move to a selected position within a continuous range between a first position and a second position.

35. (Original) The method of claim 34, wherein the plate and the dielectric liquid are transparent.

36. (Original) The method of claim 34, wherein interposing the reflective element between the surface of the substrate and the plate includes submerging the reflective element in the dielectric liquid.

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37. (Original) The method of claim 34, wherein interposing the reflective element between the surface of the substrate and the plate includes positioning the reflective element above the dielectric liquid.

10 38. (Original) The method of claim 34, wherein the second position of the reflective element is oriented at an angle to the first position.

39. (Original) The method of claim 34, further comprising:
extending at least one post from the surface of the substrate, wherein interposing
15 the reflective element between the surface of the substrate and the transparent plate includes supporting the reflective element relative to the surface of the substrate from the at least one post.

40. (Original) The method of claim 39, further comprising:
20 extending at least one hinge between the at least one post and the reflective element, wherein the at least one hinge is adapted to facilitate movement of the reflective element between the first position and the at least one second position.

41. (Original) The method of claim 40, wherein the at least one hinge includes a
25 torsional member adapted to twist about a longitudinal axis thereof.

42. (Original) The method of claim 40, wherein the at least one hinge includes a flexure member adapted to bend along a longitudinal axis thereof.

30 43. (Original) The method of claim 39, further comprising:
extending a conductive via through the at least one post and electrically coupling the conductive via with the reflective element.

44. (Original) A micro-mirror device fabricated by the method of claim 34.